

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Atsushi SHIOTA, et al,

SERIAL NO: 09 770,289

APR 18 2003

GAU: 1712

FILED: January 29, 2001

EXAMINER: M. FEELY

FOR: PROCESS FOR PRODUCING SILICA-BASED FILM, SILICA-BASED FILM, INSULATING FILM,  
AND SEMICONDUCTOR DEVICE

REQUEST FOR EXTENSION OF TIME  
UNDER 37 C.F.R. 1.136

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

RECEIVED  
APR 22 2003  
TC 1700

SIR:

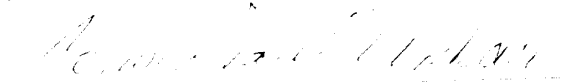
It is hereby requested that a **one** month extension of time be granted to April 18, 2003 for

- ☒ filing a response to the Official Action dated: December 18, 2002.
- ☐ responding to the requirements in the Notice of Allowability dated:
- ☐ filing the Formal Drawings. The Issue Fee due has been timely filed.
- ☐ responding to the Notice to File Missing Parts of Application dated:
- ☐ filing a Notice of Appeal. A timely response to the final rejection, due has been filed.
- ☐ filing an Appeal Brief. A Notice of Appeal was filed on:
- ☐ Applicant claims small entity status. See 37 CFR 1.27. Therefore, the fee amount shown below is reduced by one-half.

The required fee of \$110.00 is enclosed herewith by check and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



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